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Leonard Forbes, et al.FILING DATE  
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## U.S. PATENT DOCUMENTS

*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
K.N.	AA	6,246,076	06/01	Lipkin, et al.		

## FOREIGN PATENT DOCUMENTS

Document Number	Date	Country	Class	Subclass	Translation	
					Yes	No
AB						

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

K.N.	AC	S. Ogawa, et al., Silicon-Aluminum Oxynitride Composite Films Deposited by Reactive Ion Beam Sputtering.	IEEE 1999, pp. 775-778.
	AD		
	AE		
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	AI		
	AJ		

EXAMINER

Khrenmugayev

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